

on-chip inductor 10

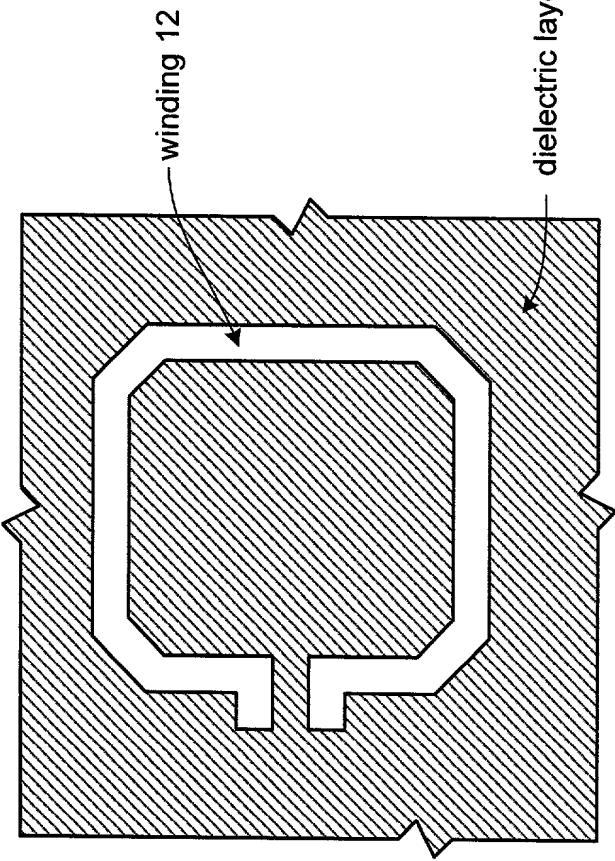


FIG. 1A
top view

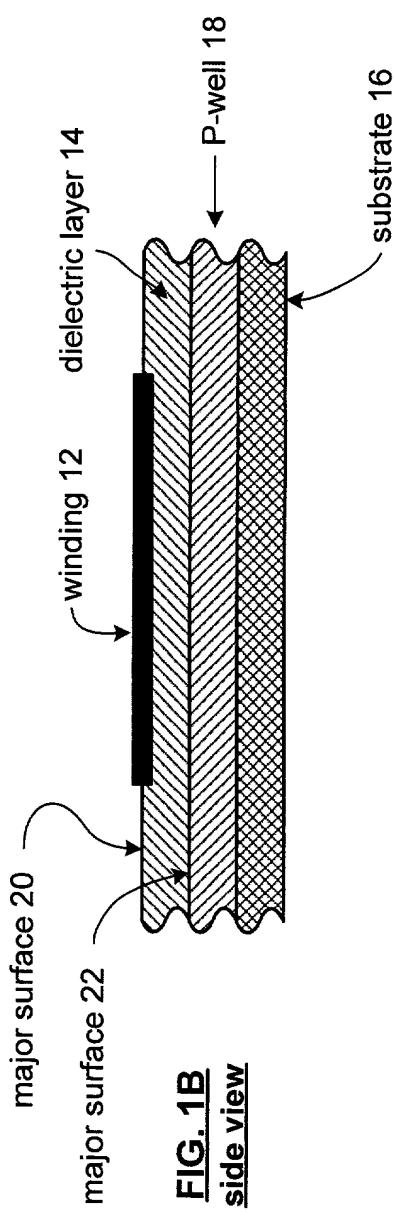


FIG. 1B
side view

on-chip inductor 25

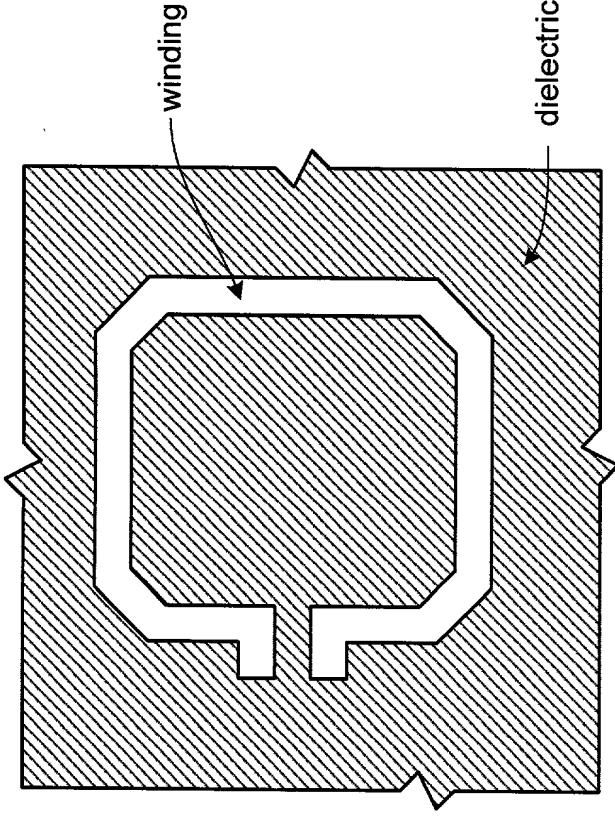


FIG. 2A
top view

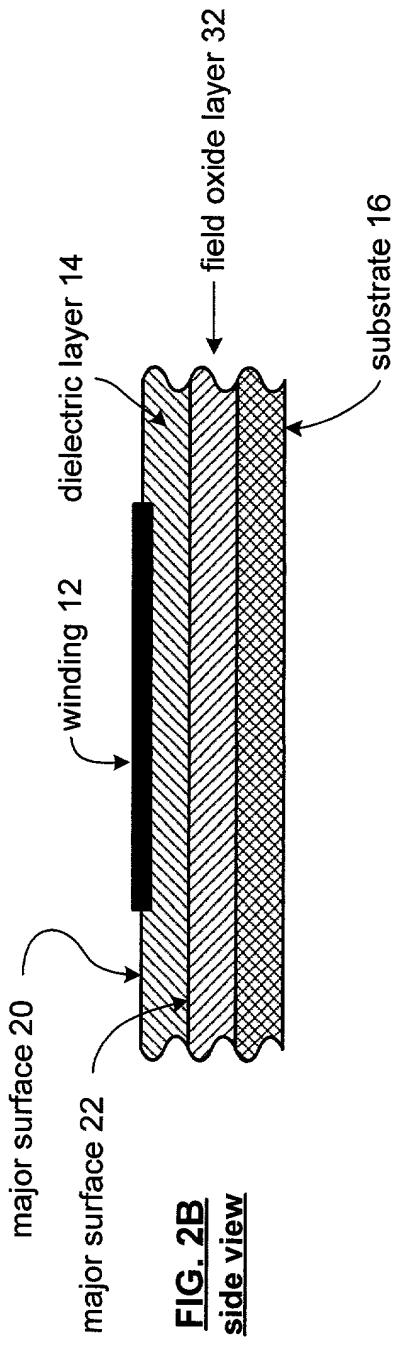
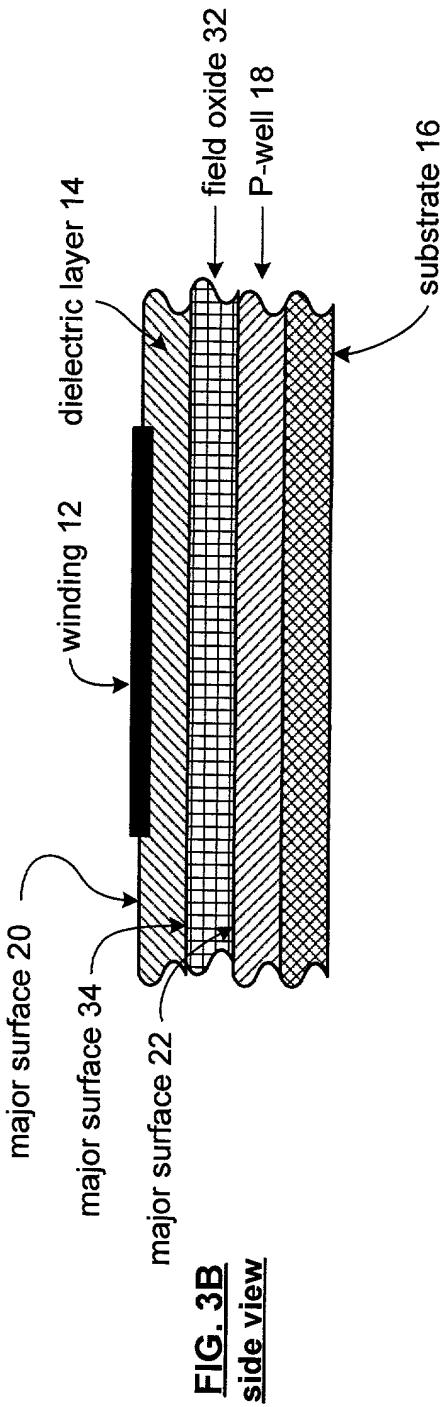
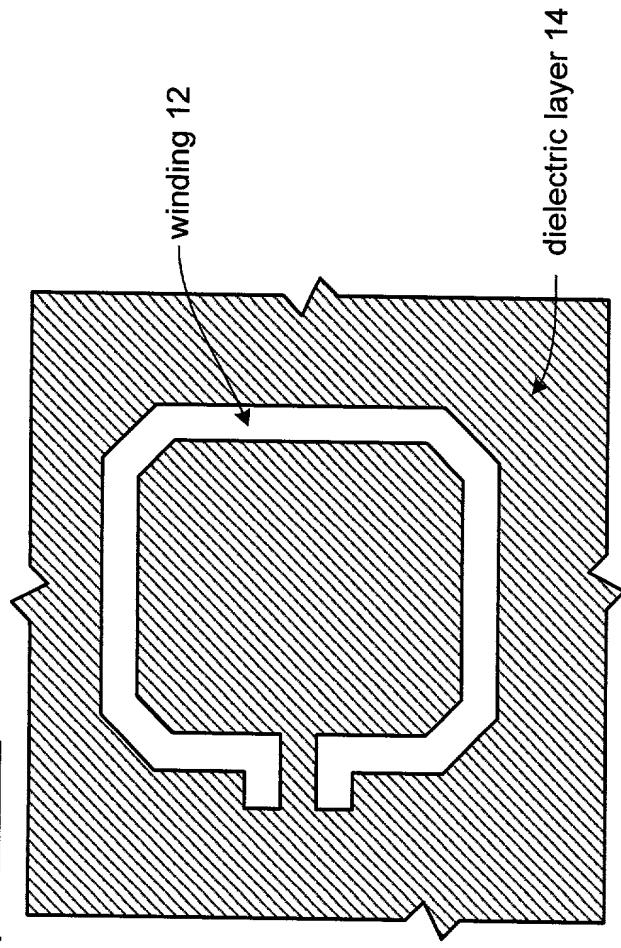


FIG. 2B
side view

on-chip inductor 30

FIG. 3A
top view



on-chip inductor 40

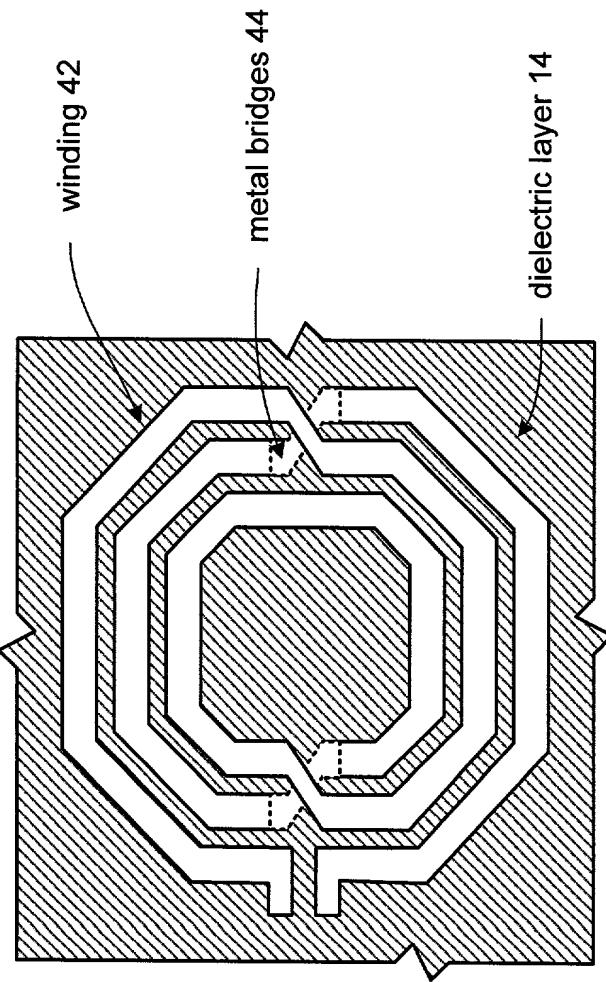


FIG. 4A
top view

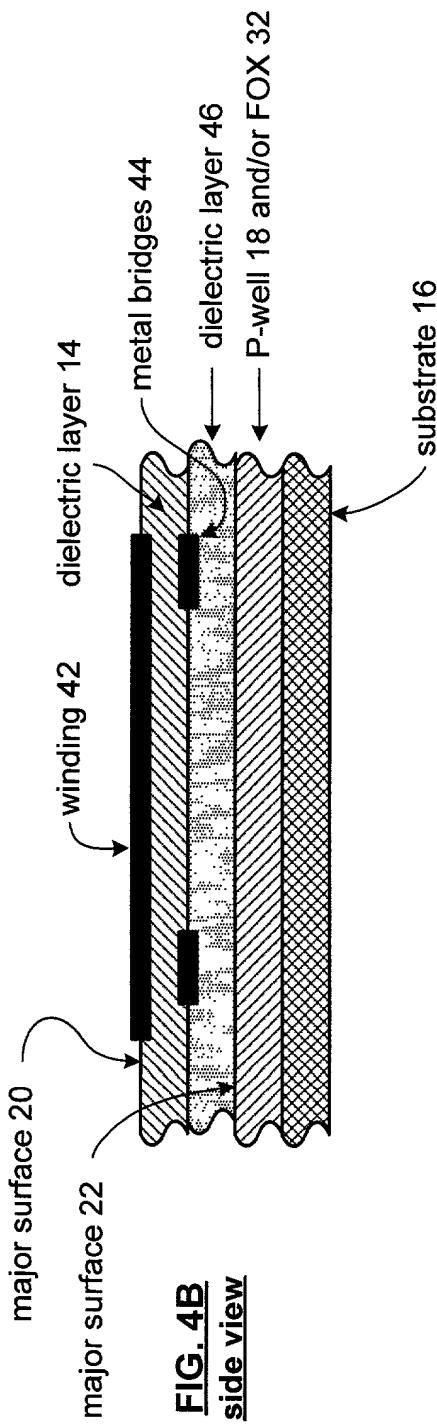


FIG. 4B
side view

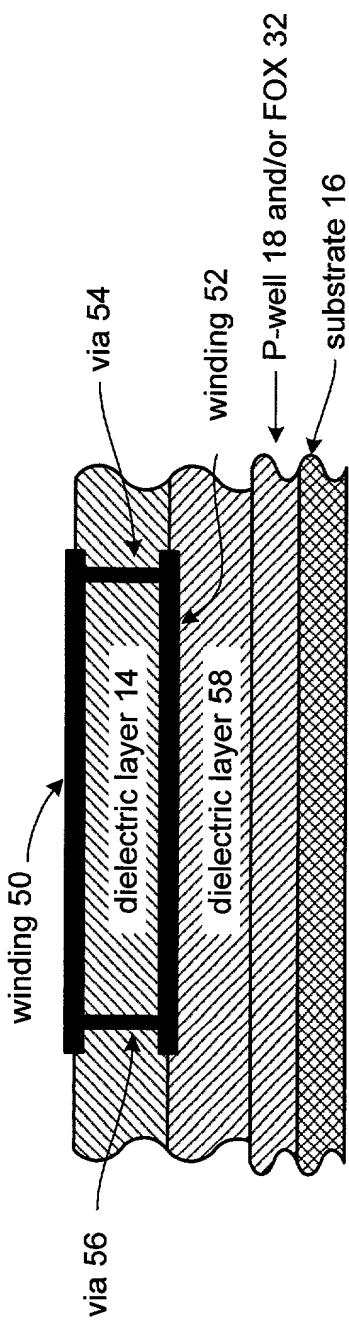


FIG. 5

differential inductor 60

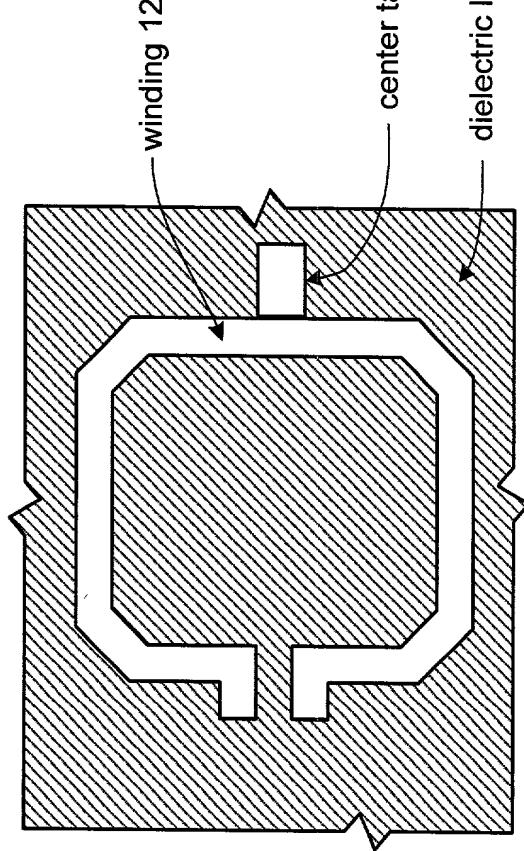


FIG. 6A
top view

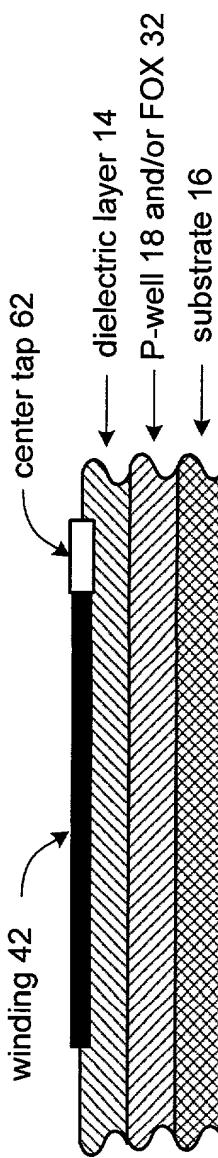
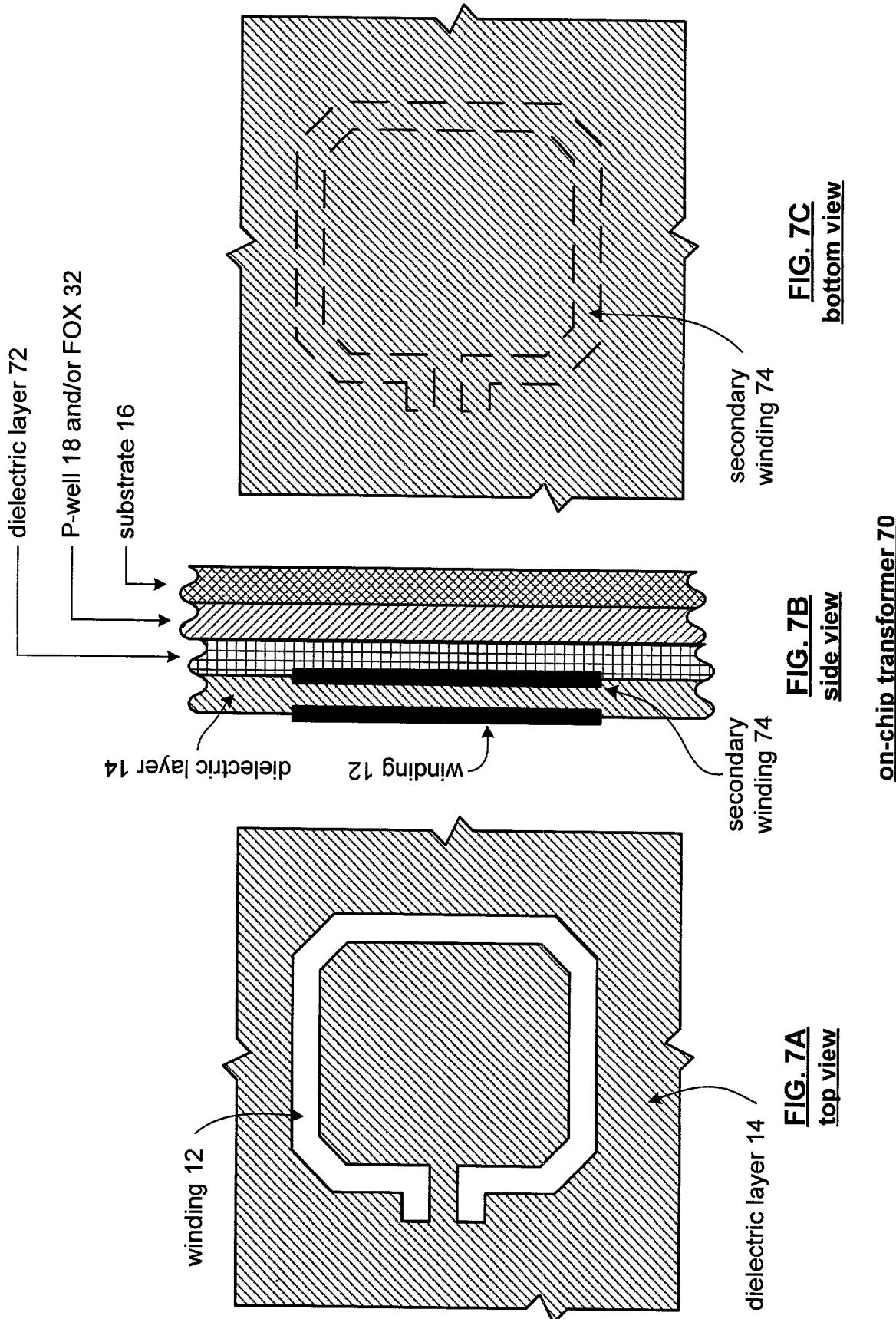


FIG. 6B
side view



on-chip inductor 80

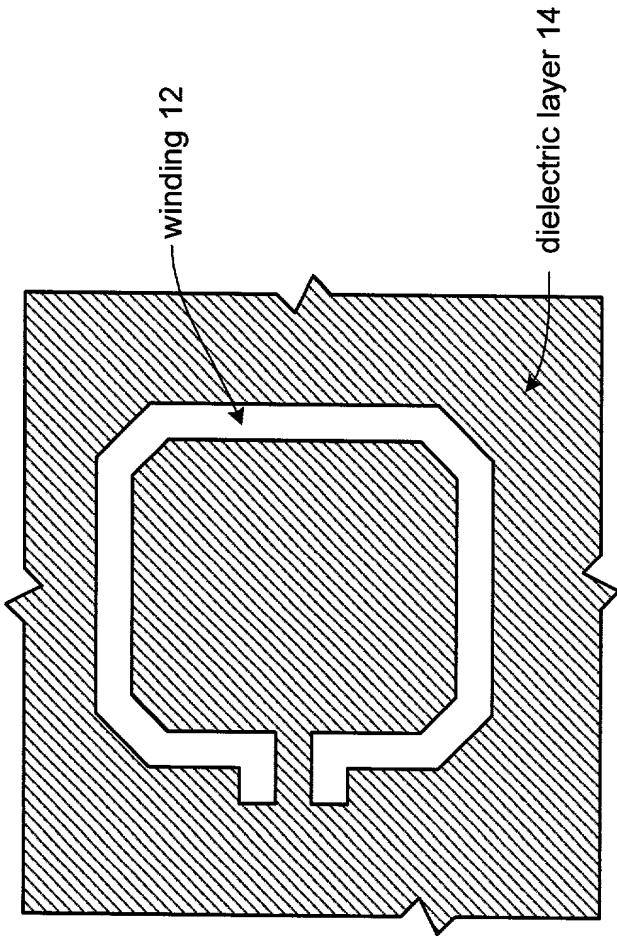


FIG. 8A
top view

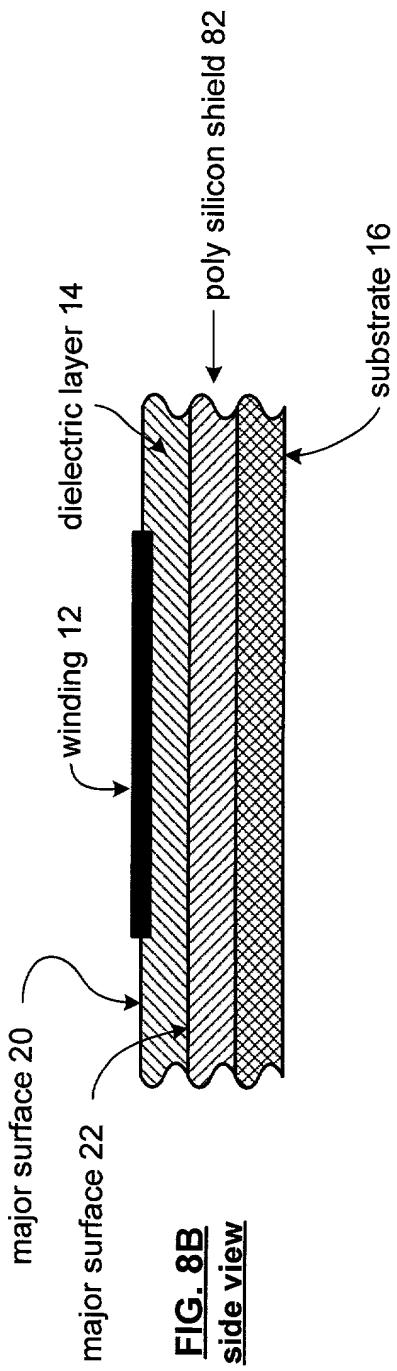


FIG. 8B
side view

start
90
create at least one dielectric layer
92
create at least one conductive winding
on the at least one dielectric layer
94
creating a P-well and/or a field oxide
layer OR a poly silicon shield on a
substrate

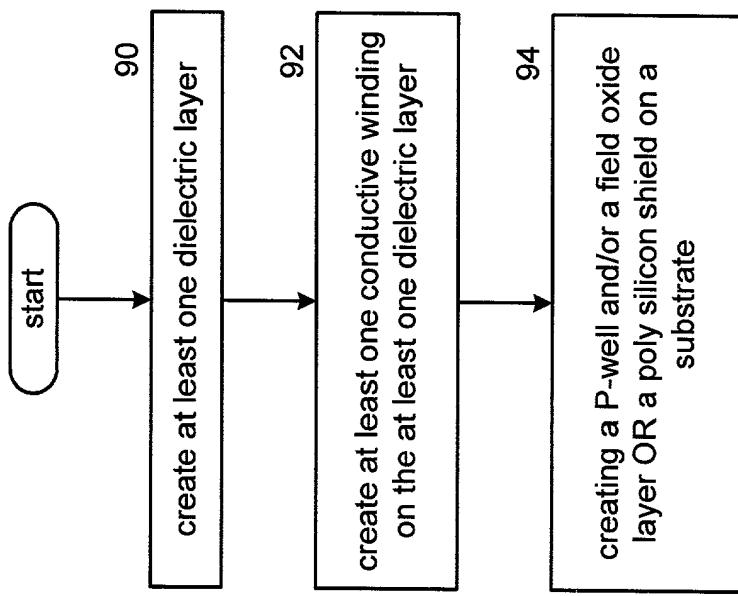


FIG. 9